

## PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1  
Stylesheet Version v1.2

EPAS ID: PAT5156843

<b>SUBMISSION TYPE:</b>	NEW ASSIGNMENT
<b>NATURE OF CONVEYANCE:</b>	ASSIGNMENT
<b>CONVEYING PARTY DATA</b>	
<b>Name</b>	<b>Execution Date</b>
LINGYUN JIA	09/19/2018
VILJAMI J. PORE	09/10/2018
MARKO TUOMINEN	09/14/2018
SUN JA KIM	09/10/2018
ORESTE MADIA	09/10/2018
EVA TOIS	09/12/2018
SUVI HAUKKA	09/17/2018
TOSHIYA SUZUKI	09/19/2018
<b>RECEIVING PARTY DATA</b>	
<b>Name:</b>	ASM IP HOLDING B.V.
<b>Street Address:</b>	VERSTERKERSTRAAT 8
<b>City:</b>	ALMERE
<b>State/Country:</b>	NETHERLANDS
<b>Postal Code:</b>	1322 AP
<b>PROPERTY NUMBERS Total: 1</b>	
<b>Property Type</b>	<b>Number</b>
Application Number:	15971601
<b>CORRESPONDENCE DATA</b>	
<b>Fax Number:</b>	(949)760-9502
<i>Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.</i>	
<b>Phone:</b>	949-760-0404
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<b>Correspondent Name:</b>	KNOBBE MARTENS OLSON & BEAR LLP
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<b>Address Line 4:</b>	IRVINE, CALIFORNIA 92614
<b>ATTORNEY DOCKET NUMBER:</b>	ASMMC.145AUS
<b>NAME OF SUBMITTER:</b>	ANDREW N. MERICKEL
<b>SIGNATURE:</b>	/ANDREW N. MERICKEL/

PATENT

<b>DATE SIGNED:</b>	09/25/2018
	This document serves as an Oath/Declaration (37 CFR 1.63).
<b>Total Attachments: 9</b> source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page1.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page2.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page3.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page4.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page5.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page6.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page7.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page8.tif source=2018-09-24 Executed Declaration_Assignment-ASMMC.145AUS#page9.tif	

**COMBINED DECLARATION & ASSIGNMENT (37 CFR 1.63(e))**

*Application Data Sheet filed previously or concurrently*

Docket No.: ASMMC.145AUS

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Title: PLASMA ENHANCED DEPOSITION PROCESSES FOR CONTROLLED FORMATION OF METAL OXIDE THIN FILMS

Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

***Declaration***

This Declaration is directed to the application identified above that:

Was filed **May 4, 2018** as U.S. or International Application No. **15/971,601** and incorporating any amendments made thereto prior to the signature date of this Declaration.

As a named inventor, I declare that:

The above-identified application was made or authorized to be made by me.

I believe that I am the original inventor or an original joint inventor of a claimed invention in the application.

I hereby acknowledge that any willful false statement made in this declaration is punishable under 18 USC 1001 by fine or imprisonment of not more than five (5) years, or both.

I have reviewed and understand the contents of the above-identified application, including the claims, as amended by any amendment.

I acknowledge the duty to disclose information which is material to patentability as defined in 37 CFR 1.56.

***Assignment from Inventors***

WHEREAS, **above-identified inventors** (individual(s) hereinafter "ASSIGNOR") invented certain new and useful improvements, technology, inventions, developments, ideas, ornamental designs, or discoveries, and hereby assign or are under an obligation to assign to the below identified Assignee the above-titled application (collectively hereinafter referred to as the "Work") for which an application for Letters Patent in the United States (identified above) has been prepared for filing with the United States Patent and Trademark Office (hereinafter the "Application").

AND WHEREAS, **ASM IP HOLDING B.V.**, with its principal place of business at Versterkerstraat 8, Almere, 1322 AP, The Netherlands (hereinafter the "ASSIGNEE"), desires to acquire the entire right, title, and interest in and to the Application and the Work.

NOW, THEREFORE, for good and valuable consideration of which receipt is hereby acknowledged, ASSIGNOR hereby acknowledges that ASSIGNOR has sold, assigned, transferred and set over, and by these presents does hereby sell, assign, transfer and set over, unto said ASSIGNEE, its successors, legal representatives and assigns, the entire right, title, and interest throughout the world in the Application and the Work, including all Patent Properties filed or issued upon the Application and the Work; where "Patent Properties" include, but are not limited to:

all provisional applications relating thereto (including but not limited to U.S. Provisional Application No(s). **62/502,118**, filed **May 5, 2017**, and **62/507,078**, filed **May 16, 2017** (respectively if plural applications));

all nonprovisional applications claiming priority to aforementioned provisional(s) and/or the present Application, including, all divisions, continuations, continuations-in-part, and reissues, and all Letters Patent of the United States which may be granted thereon and all reissues and extensions thereof; and

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Inventors: Lingyun Jia, Vijjami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

all rights of priority under International Conventions and any related Letters Patent which may hereafter be granted or filed in any country or countries foreign to the United States, all extensions, renewals and reissues thereof.

ASSIGNOR hereby acknowledges the ASSIGNEE as the Applicant for all aforementioned Patent Properties, and authorizes and requests the Commissioner of Patents of the United States, and any Official of any country or countries foreign to the United States, whose duty it is to issue patents on applications as aforesaid, to issue all related Letters Patent to the ASSIGNEE, its successors, legal representatives and assigns, in accordance with the terms of this instrument.

AND ASSIGNOR DOES HEREBY sell, assign, transfer, and convey to ASSIGNEE, its successors, legal representatives, and assigns all claims for damages and all remedies arising out of any violation of the rights assigned hereby that may have accrued prior to the date of assignment to ASSIGNEE, or may accrue hereafter, including, but not limited to, the right to sue for, collect, and retain damages for past infringements of said Letters Patent before or after issuance.

AND ASSIGNOR DOES HEREBY covenant and agree that ASSIGNOR will communicate to said ASSIGNEE, its successors, legal representatives and assigns, any facts known to ASSIGNOR respecting the Work, and testify in any legal proceeding, assist in the preparation of any other Patent Property relating to the Application and the Work or any improvements made thereto, sign/execute all lawful papers, authorize the filing of and execute and make all rightful oaths and/or declarations in connection with the Application and the Work including any improvements made thereto, any patent applications filed therefrom, and any continuing application filed from any of the aforementioned applications, and generally do everything possible to aid the ASSIGNEE, its successors, legal representatives and assigns, to obtain and enforce proper patent protection for the Work in all countries.

Legal Name of inventor: Lingyun Jia

Signature: \_\_\_\_\_

*Lingyun Jia*

Date: \_\_\_\_\_

*2018-09-19*

Witnessed by: \_\_\_\_\_

*Junya Morimoto*

Witness Name (printed): \_\_\_\_\_

*Junya Morimoto*

**COMBINED DECLARATION & ASSIGNMENT (37 CFR 1.63(e))**

*Application Data Sheet filed previously or concurrently*

Docket No.: ASMMC.145AUS

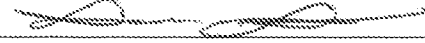
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Title: PLASMA ENHANCED DEPOSITION PROCESSES FOR CONTROLLED FORMATION OF METAL OXIDE THIN FILMS

Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

Legal Name of inventor: Viljami J. Pore

Signature:  Date: Sept 10 2018

Witnessed by: 

Witness Name (printed): HAANO HUOTARI

**COMBINED DECLARATION & ASSIGNMENT (37 CFR 1.63(e))**

*Application Data Sheet filed previously or concurrently*

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Title: PLASMA ENHANCED DEPOSITION PROCESSES FOR CONTROLLED FORMATION OF METAL OXIDE THIN FILMS

Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

Legal Name of inventor: Marko Tuominen

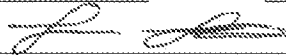
Signature: \_\_\_\_\_

Date: \_\_\_\_\_

Witnessed by: \_\_\_\_\_

Witness Name (printed): \_\_\_\_\_

14/9/2015



MARKO TUOMINEN

**COMBINED DECLARATION & ASSIGNMENT (37 CFR 1.63(e))**

*Application Data Sheet filed previously or concurrently*


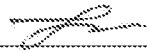
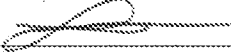
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Title: PLASMA ENHANCED DEPOSITION PROCESSES FOR CONTROLLED FORMATION OF METAL OXIDE THIN FILMS

Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

Legal Name of inventor: Sun Ja Kim

Signature:  \_\_\_\_\_ Date: 10-Sep-2018  
Witnessed by:   \_\_\_\_\_  
Witness Name (printed): MARKO TUOMINEN EURO OTARU

**COMBINED DECLARATION & ASSIGNMENT (37 CFR 1.63(e))**

*Application Data Sheet filed previously or concurrently*

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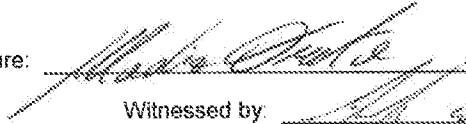
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Title: PLASMA ENHANCED DEPOSITION PROCESSES FOR CONTROLLED FORMATION OF METAL OXIDE THIN FILMS

Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

Legal Name of inventor: Oreste Madia

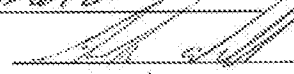
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Date: \_\_\_\_\_

10/08/2018

Witnessed by \_\_\_\_\_



Witness Name (printed) \_\_\_\_\_

10/09/18



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Title: PLASMA ENHANCED DEPOSITION PROCESSES FOR CONTROLLED FORMATION OF METAL OXIDE THIN FILMS

Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

Legal Name of inventor: Eva Tois

Signature: *Eva Tois* Date: *12-Sept. 2018*

Witnessed by: *Varun*

Witness Name (printed): *Varun Sharma*

**COMBINED DECLARATION & ASSIGNMENT (37 CFR 1.63(e))**

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Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Ja Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

Legal Name of inventor: Suvi Haukka

Signature: \_\_\_\_\_

Date: \_\_\_\_\_

September 17, 2018

Witnessed by: \_\_\_\_\_

Witness Name (printed): \_\_\_\_\_

Kirsi Kylänpää

**COMBINED DECLARATION & ASSIGNMENT (37 CFR 1.63(e))**

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Inventors: Lingyun Jia, Viljami J. Pore, Marko Tuominen, Sun Jia Kim, Oreste Madia, Eva Tois, Suvi Haukka, Toshiya Suzuki

Legal Name of Inventor: Toshiya Suzuki

Signature:  Date: 9.19.2018

Witnessed by: 鈴木靖生

Witness Name (printed): YASUO SUZUKI